



WORLD CUSTOMS ORGANIZATION
ORGANISATION MONDIALE DES DOUANES

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HARMONIZED SYSTEM
REVIEW SUB-COMMITTEE

NR0042E1

-
19th Session

O. Eng.

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Brussels, 15 March 1999.

POSSIBLE SEPARATE IDENTIFICATION OF EQUIPMENT
FOR THE MANUFACTURE OF SEMICONDUCTOR DEVICES AND FLAT PANEL DISPLAYS

(Item II.A.2 on Agenda)

Reference documents :

42.223 (RSC/18)
42.500, Annex A/3 (RSC/18 – Report)
NR0003

I. BACKGROUND

1. Subsequent to the preparation of Doc. NR0003E1, the Secretariat received, on 10 March 1999, the following Note from the Japanese Administration on the possible separate identification of equipment for the manufacture of semiconductor devices and flat panel displays (FPDs).

II. PROPOSAL BY JAPAN

“ **84.85** **Machines and apparatus for the manufacture [, process or assembly] of semiconductor devices [and flat panel displays] as defined in Note 9 to this Chapter.**

- 8485.20 - For manufacturing masks or reticles
- 8485.30 - For manufacturing wafers
- For processing wafers :
- 8485.41 -- Direct write-on wafer apparatus for drawing of circuit patterns on sensitised semiconductor materials
- 8485.42 -- Step and repeat aligners for the projection of circuit patterns on sensitised semiconductor materials
- 8485.43 -- Other apparatus for the projection or drawing of circuit patterns on sensitised semiconductor materials

File No. 2581

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- 8485.44 -- For dry-etching patterns on semiconductor materials
- 8485.45 -- Ion implanters for doping semiconductor materials
- 8485.49 -- Other
- 8485.50 - For assembling semiconductor devices
- 8485.70 - Other
- 8485.80 - Parts and accessories.”

“90.33 Instruments and apparatus for testing [, measuring], inspecting and checking semiconductor devices [and flat panel displays] as defined in Note 7 to this Chapter.

- 9033.10 - For testing [, measuring], inspecting and checking masks or reticles
- 9033.20 - For testing [, measuring], inspecting and checking wafers
- 9033.30 - For inspecting semiconductor devices
- 9033.80 - Other
- 9033.90 - Parts and accessories.”

III. SECRETARIAT COMMENTS

2. The Committee is invited to take account of the note from the Japanese Administration when examining this agenda item.
